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(54) Title (EN): STRAIN SENSOR AND STRAIN MEASUREMENT METHOD

(54) Title (FR): CAPTEUR DE CONTRAINTE ET PROCÉDÉ DE MESURE DE CONTRAINTE

(54) Title (JA): ひずみセンサ、及びひずみ測定方法

(57) Abstract:

(EN): According to the present invention, a strain sensor (100) installed inside a device under test comprises a flat plate-form distortion-inducing plate (F), a strain gauge (112) affixed to the distortion-inducing plate, and a pair of protruding parts (P1, P2) that protrude from the distortion-inducing plate toward both sides along an in-plane direction of the distortion-inducing plate. The strain gauge is affixed to a region (SC) of the distortion-inducing plate that is sandwiched between the pair of protruding parts.

(FR): Selon la présente invention, un capteur de contrainte (100) installé à l'intérieur d'un dispositif à l'essai comprend une plaque d'induction de distorsion en forme de plaque plate (F), une jauge de contrainte (112) fixée à la plaque d'induction de distorsion, et une paire de parties en saillie (P1, P2) qui font saillie à partir de la plaque d'induction de distorsion vers les deux côtés le long d'une direction dans le plan de la plaque d'induction de distorsion. La jauge de contrainte est fixée à une région (SC) de la plaque d'induction de distorsion qui est prise en sandwich entre la paire de parties saillantes.

(JA): 被験体の内部に設置されるひずみセンサ(100)は、平板状の起歪板(F)と、前記起歪板に貼り付けられたひずみゲージ(112)と、前記起歪板の面内方向に沿って前記起歪板から両側に突出する一対の突出部(P1、P2)とを備える。前記起歪板の、前記一対の突出部に挟まれた領域(SC)に前記ひずみゲージが貼り付けられている。

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